

Notice of References Cited	Application/Control No. 10/522,688		Applicant(s)/Patent Under Reexamination CHOQUET ET AL.	
	Examiner Mark L. Shevin		Art Unit 1793	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,322,859	11-2001	Pluim et al.	427/585
*	B	US-5,397,652	03-1995	Carey et al.	428/610
*	C	US-4,940,522	07-1990	Kagechika et al.	204/192.1
*	D	US-5,073,403	12-1991	Kagechika et al.	427/528
*	E	US-5,270,081	12-1993	Manier et al.	427/534
*	F	US-5,397,652	03-1995	Carey et al.	428/610
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	K	US-			
	L	US-			
	M	US-			

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	N	WO 96/22841	08-1996	US	STINET et al	B05C 11/00
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NON-PATENT DOCUMENTS

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	U	"Surface Engineering of Carbon and Alloy Steels" in Vol. 5: Surface Engineering, ASM Handbook, 1994			
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.